Spring semester of 2018/2019 academic year

Ralchenko Viktor G.
Course Schedule

WEDNESDAY

10:15 — 13:30	■ SEM Plasma CVD of thin-film structures; Plasma Cvd of Thin-film Structures **(2019-02-06 — 2019-04-10)** 👥 M17-303, M17-313, M17-393 📍 IOF RAN
13:35 — 14:20	■ LEC Plasma CVD of thin-film structures; Plasma Cvd of Thin-film Structures **(2019-02-06 — 2019-03-06)** 👥 M17-303, M17-313, M17-393 📍 IOF RAN